

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Y. KURATA, et al.

Serial No.: 10/049,672

35 USC 371 Date: APRIL 30, 2002

Title: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL  
POLISHING, AND METHOD OF POLISHING SUBSTRATE  
MEMBER

Group AU: 1765

Examiner: Duy Vu Nguyen Deo

Confirm. No: 7706

**AMENDMENT**

**Mail Stop: AMEND - FEE**

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

March 21, 2008

Sir:

In response to the Office Action dated September 21, 2007, the period for response having been extended for three (3) months by the attached Petition for Extension of Time, please amend the above-identified application as listed in the following, and as set forth on the following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.